Supplemental information

Fig. S1. The XPS depth profile for oxide formed at 450ºC without hydrogen annealing

Fig. S2. The XPS depth profile for oxide formed at 450ºC with hydrogen annealing

Fig. S3. The XPS survey at the depth of 200 nm for oxide formed at 750ºC without hydrogen annealing

Fig. S4. The XPS survey at the depth of 360 nm for oxide formed at 750ºC with hydrogen annealing

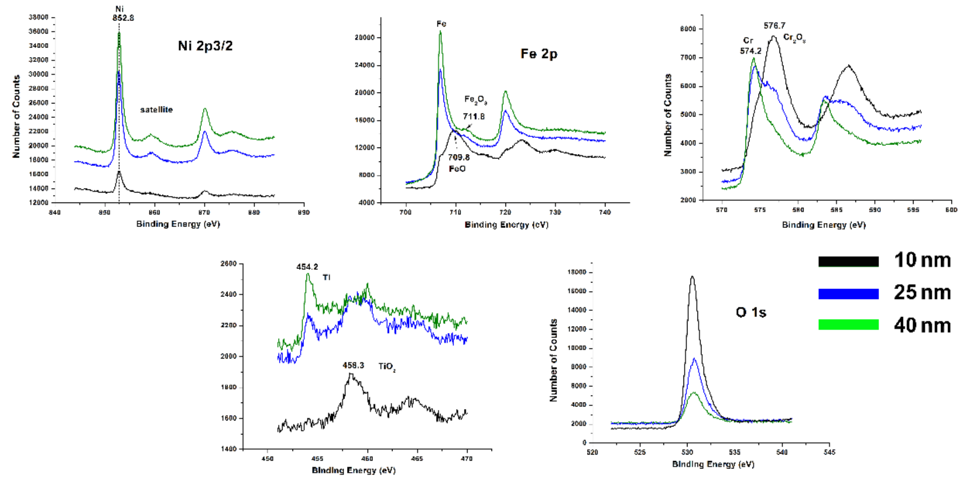

Fig. S1.

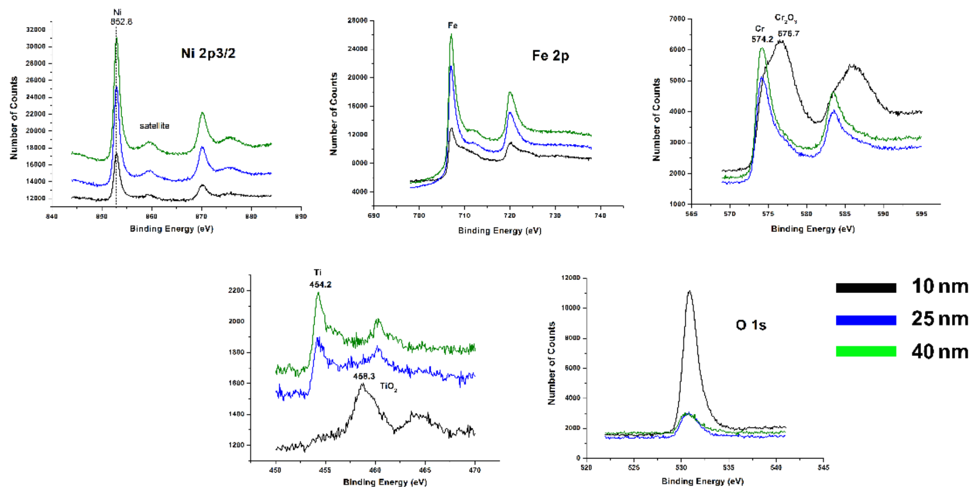

Fig. S2.

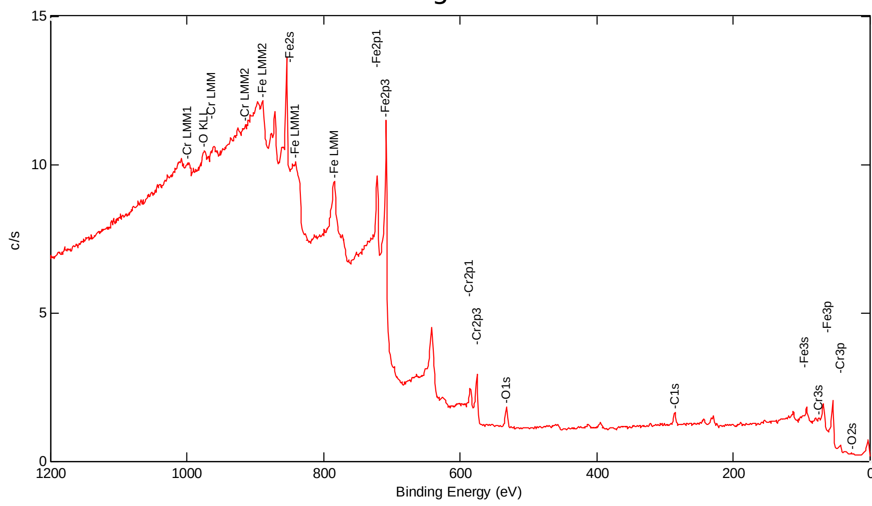

Fig. S3.

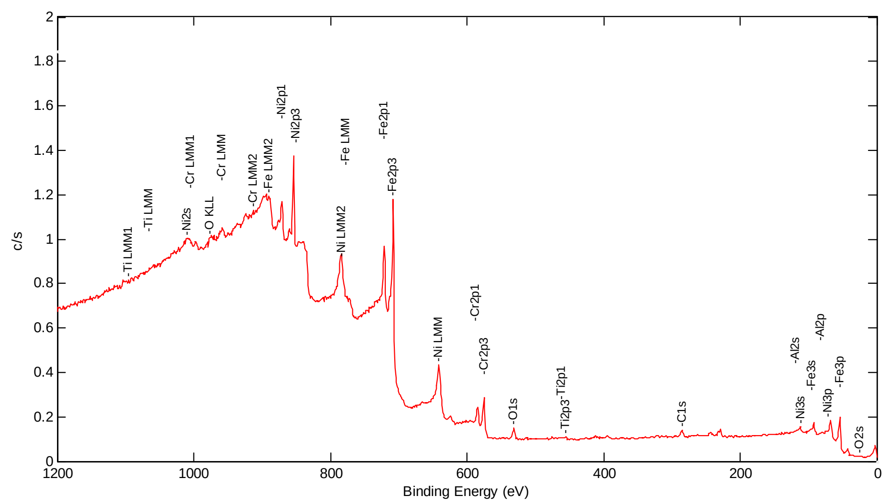

Fig. S4.